

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :
Shinsuke YAMANAKA et al. : **Mail Stop: PCT**
Serial No. NEW : Attorney Docket No. 2005_0973A
Filed June 21, 2005 :

OXIDE NANOSTRUCTURE, METHOD FOR
PRODUCING SAME, AND USE THEREOF
[Corresponding to PCT/JP2003/015961
Filed December 12, 2003]

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to the provisions of 37 CFR 1.56, 1.97 and 1.98, Applicants request consideration of the references listed on attached form PTO-1449 and any additional information identified below in paragraph 3. A legible copy of each reference listed on the Form PTO-1449 is enclosed, except a copy is not provided for:

- ☒ each U.S. Patent and U.S. Patent application publication;
- ☐ each reference previously cited in the international application
PCT/_____; and/or
- ☐ each reference previously cited in prior parent application Serial No.
_____.

1a. ☒ This Information Disclosure Statement is submitted:

within three months of the filing date (or of entry into the National Stage) of the
above-entitled application, **or**

before the mailing of a first Office Action on the merits or the mailing of a first Office Action after the filing of an RCE,

and thus no certification and/or fee is required.

1b. ☐ This Information Disclosure Statement is submitted

after the events of above paragraph 1a and prior to the mailing date of a final Office Action or a Notice of Allowance or an action which otherwise closes prosecution in the application, and thus:

(1) ☐ the certification of paragraph 2 below is provided, **or**

(2) ☐ the fee of \$180.00 specified in 37 CFR 1.17(p) is enclosed.

1c. ☐ This Information Disclosure Statement is submitted:

after the mailing date of a final Office Action or Notice of Allowance or action which otherwise closes prosecution in the application, and prior to payment of the issue fee, and thus:

the certification of paragraph 2 below is provided, and

the fee of \$180.00 specified in 37 CFR 1.17(p) is enclosed.

2. It is hereby certified


- a. ☐ that each item of information contained in this Information Disclosure Statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the Statement, or
- b. ☐ that no item of information contained in the Information Disclosure Statement was cited in a communication from a foreign patent office in a counterpart foreign application and, to the knowledge of the person signing the certification after making reasonable inquiry, was known to any individual designated in §1.56(c) more than three months prior to the filing of the Statement.

3. ☐ Consideration of the following list of additional information (including any copending or abandoned U.S. application, prior uses and/or sales, etc.) is requested.
4. For each non-English language reference listed on the attached form PTO-1449, reference is made to:
- a. ☒ a full or partial English language translation submitted herewith,
 - b. ☒ a foreign patent office (International) search report (in the English language) submitted herewith (Attachment F),
 - c. ☒ the concise explanation contained in the specification of the present application at page 1,
 - d. ☒ the concise explanation set forth in the attached English language abstract,
 - e. ☐ the concise explanation set forth below or on a separate sheet attached to the reference:
5. ☐ A foreign patent office search report citing one or more of the references is enclosed.

Respectfully submitted,

Shinsuke YAMANAKA et al.

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

By 
Matthew M. Jacob
Registration No. 25,154
Attorney for Applicants

MJ/kes
Washington, D.C. 20006-1021
Telephone (202) 721-8200
Facsimile (202) 721-8250
June 21, 2005

FORM PTO 1449 (modified)

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICELIST OF REFERENCES CITED BY APPLICANT(S)
(Use several sheets if necessary)

Date Submitted to PTO: June 21, 2005

ATTY DOCKET NO.
2005_0973A

SERIAL NO.

CLASS

10/540231

APPLICANT
Shinsuke YAMANAKA et al.FILING DATE
June 21, 2005

GROUP

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES NO
	AH	2001-270717 A	10/2001	JP			X
	AI	0832847 A1	04/1998	EP			
	AJ	2001-342014 A	12/2001	JP			X
	AK	54-116350 A	09/1979	JP			abstract
	AL	52-34434 A	03/1977	JP			abstract
	AM	52-53740 A	04/1977	JP			abstract
	AN	0262893 A2	09/1987	EP			
	AO	95/11007 A1	04/1995	WO			

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

AP	Hideaki MASUDA et al., "The Fabrication of Porous TiO ₂ Films Using Two-Step Replication of Microstructure of Anodic Alumina", <i>Jpn. J. Appl. Phys.</i> Vol. 31 (1992) pp. L1775-L1777 Part 2, No. 12B, 15 December 1992.
AQ	Takashi SUGIURA et al., "The control of a minute structure of TiO ₂ surface by a photoelectrochemical etching", 18 th Discussion about Solid and Surface Photochemistry, November 1999.

EXAMINER

DATE CONSIDERED